



NEW

PATENT APPLICATION

THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Syo-ichi TAKAMIZAWA et al.

ATTN: **Mail Stop PCT**

Application No.: 10/578,369

Docket No.: 127101

Filed: May 5, 2006

For: **METHOD FOR PRODUCING SILICON EPITAXIAL WAFER**

CORRECTED FILING RECEIPT STATUS REQUEST

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

A Request for Correction of PALM Records was filed on December 12, 2006. A copy of the Request and a copy of the Patent Office date-stamped acknowledgement receipt are attached hereto.

The corrected Filing Receipt has not yet been received. It is respectfully requested that the corrected Filing Receipt be immediately forwarded to the attorneys of record at the address set forth below.

If there are any questions regarding this matter, please contact the undersigned at the telephone number set forth below.

Respectfully submitted,

William P. Berridge
Registration No. 30,024

Randi B. Isaacs
Registration No. 56,046

WPB:RBI/amb
Date: July 10, 2007

OLIFF & BERRIDGE, PLC
P.O. Box 19928
Alexandria, Virginia 22320
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TFW

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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Attn: OIPE

Syo-ichi TAKAMIZAWA et al.

Group Art Unit: 2812

Application No.: 10/578,369

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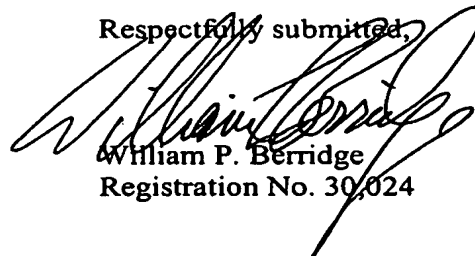
REQUEST FOR CORRECTION OF PALM RECORDS

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Attached is a photocopy of the original filing receipt on which errors have been corrected in red. These errors are being brought to the attention of the Patent and Trademark Office so that it may correct its records.

Respectfully submitted,



William P. Berridge
Registration No. 30,024

WPB:amb

Date: December 12, 2006

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**DEPOSIT ACCOUNT USE
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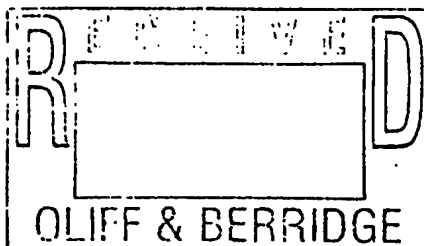
UNITED STATES PATENT AND TRADEMARK OFFICE

AMB

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APPL NO.	FILING OR 371 (c) DATE	ART UNIT	FIL FEE REC'D	ATTY. DOCKET NO	DRAWINGS	TOT CLMS	IND CLMS
10/578,369	05/05/2006	2812	1150	127101	2	25	2

25944
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CONFIRMATION NO. 8987

FILING RECEIPT



OC000000021392954

Date Mailed: 12/01/2006

Receipt is acknowledged of this regular Patent Application. It will be considered in its order and you will be notified as to the results of the examination. Be sure to provide the U.S. APPLICATION NUMBER, FILING DATE, NAME OF APPLICANT, and TITLE OF INVENTION when inquiring about this application. Fees transmitted by check or draft are subject to collection. Please verify the accuracy of the data presented on this receipt. If an error is noted on this Filing Receipt, please mail to the Commissioner for Patents P.O. Box 1450 Alexandria Va 22313-1450. Please provide a copy of this Filing Receipt with the changes noted thereon. If you received a "Notice to File Missing Parts" for this application, please submit any corrections to this Filing Receipt with your reply to the Notice. When the USPTO processes the reply to the Notice, the USPTO will generate another Filing Receipt incorporating the requested corrections (if appropriate).

Applicant(s)

Anaka-shi

Syo-ichi Takamizawa, Gunma, JAPAN;
 Ryuji Sayama, Gunma, JAPAN;

Anaka-shi

Power of Attorney: The patent practitioners associated with Customer Number 25944.

Domestic Priority data as claimed by applicant

This application is a 371 of PCT/JP04/12179 08/25/2004

Foreign Applications

JAPAN 2003-385333 11/14/2003

If Required, Foreign Filing License Granted: 11/28/2006

The country code and number of your priority application, to be used for filing abroad under the Paris Convention, is **US10/578,369**

Projected Publication Date: 03/08/2007

Non-Publication Request: No

Early Publication Request: No

Title

Method for producing silicon epitaxial wafer

Preliminary Class

438

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Title 37, Code of Federal Regulations, 5.11 & 5.15**

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PTO RECEIPT FOR FILING OF PAPERS

Delivery ▶ Mail Room

The following papers have been filed:

Request for Correction of PALM Records and marked-up copy of OFR



Name of Applicant:	Syo-ichi TAKAMIZAWA; Ryuji SAYAMA
Serial No.:	10/578,369
Attorney File No.:	127101
Title:	Method for Producing Silicon Epitaxial Wafer
Sender's Initials:	WPB:amb
Assignee:	SHIN-ETSU HANDOTAI CO., LTD.

PATENT OFFICE DATE STAMP

41

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